

ABSTRACT

Substrate processing with return processing is carried out efficiently by a substrate processing apparatus that continuously processes a plurality of substrates.

5 It is equipped with a conveyor chamber constituting a substrate convey space, a plurality of process chambers in which substrate processing is carried out, substrate convey means provided in the conveyor chamber having a function of conveying substrates, and a substrate convey control means that controls the process of substrate convey by the substrate convey means so that in a case in which after a

10 substrate is continuously processed by two or more process chambers, the substrate is re-conveyed from the last process chamber to any of the two or more process chambers other than the last and return processing implemented, in the re-conveyance the substrate is conveyed to said any of the process chambers after being temporarily retracted to a place other than a process chamber.